Title of Invention: SUBSTRATE PROCESSING APPARATUS, SUBSTRATE PROCESSING SYSTEM, ELECTRICAL POWER SUPPLY SYSTEM, AND ELECTRICAL POWER SUPPLY METHOD

Abstract

There is provided a substrate processing apparatus for processing a substrate, comprising: a power receiver including a power reception coil to which power is transmitted in a non-contact manner from a power transmission coil located outside the substrate processing apparatus. The substrate processing apparatus is configured to supply power to at least one unit or member that uses power from the power receiver.

Fig. 5